

Title (en)
MICRO-ELECTROMECHANICAL SYSTEM AND METHOD FOR PRODUCTION THEREOF

Title (de)
MIKRO-ELEKTROMECHANISCHES SYSTEM UND VERFAHREN ZU DESSEN HERSTELLUNG

Title (fr)
SYSTEME MICRO-ELECTROMECHANIQUE ET PROCEDE DE FABRICATION

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Abstract (en)
[origin: WO03060940A1] The invention relates to a micro-electromechanical system comprising a substrate (S) and at least two micro-elements (1, 2), of which a first one is a switchable bistable. The micro-elements (1, 2) comprise surfaces (3a, 4a) facing each other, generated by means of a structuring method and with a minimum separation characteristic for the structuring method. The first micro-element (1) is then switched to the other stable state (B), whereupon the separation between the surfaces (3a, 4a) facing each other is smaller than the minimal separation characteristic for the structuring method. The micro-electromechanical system can be embodied as an electrostatically operated micro-switch with improved switching. Laterally and horizontally working micro-electromechanical systems with new functionality and relays with current-free closing can be produced.

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